

EAST - [10774890.wsp.1]

File View Edit Tools Window Help

Drafts
 BRS: substrate and (strained near layer and
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DBs: USPAT:EPD;JPO;DERWENT;IBM_TDB

Plurals

Default operator: OR

Highlight all hit terms initially

substrate and (strained near layer and (rough\$4 and ("2" adj nm)))

ABSTRACT Image Text HTML

	U	I	Document ID	Issue Date	Pages	Title	Current OR	Current XRef
1	<input type="checkbox"/>	<input type="checkbox"/>	US 6724008 B2	20040420	28	Relaxed silicon germanium platform for high speed CMOS electronics and high	257/19	257/190; 257/192;
2	<input type="checkbox"/>	<input type="checkbox"/>	US 6723661 B2	20040420	28	Relaxed silicon germanium platform for high speed CMOS electronics and high	438/763	438/199
3	<input type="checkbox"/>	<input type="checkbox"/>	US 6723541 B2	20040420	22	Method of producing semiconductor device and semiconductor substrate	435/166	438/172; 438/198;
4	<input type="checkbox"/>	<input type="checkbox"/>	US 6720589 B1	20040413	62	Semiconductor device	257/194	257/14
5	<input type="checkbox"/>	<input type="checkbox"/>	US 6703688 B1	20040309	28	Relaxed silicon germanium platform for high speed CMOS electronics and high	257/616	257/190; 257/192;
6	<input type="checkbox"/>	<input type="checkbox"/>	US 6677192 B1	20040113	24	Method of fabricating a relaxed silicon germanium platform having planarizing for	438/172	257/E21.129; 257/E21.445;
7	<input type="checkbox"/>	<input type="checkbox"/>	US 6656271 B2	20031202	42	Method of manufacturing semiconductor wafer method of using and utilizing the	117/94	117/84; 117/913;
8	<input type="checkbox"/>	<input type="checkbox"/>	US 6646322 B2	20031111	25	Relaxed silicon germanium platform for high speed CMOS electronics and high	257/531	257/E21.129; 257/E21.445;
9	<input type="checkbox"/>	<input type="checkbox"/>	US 6645302 B2	20031111	33	Vapor phase deposition system	118/715	427/255.34
10	<input type="checkbox"/>	<input type="checkbox"/>	US 6639925 B2	20031028	39	Optical information processing equipment and semiconductor light emitting device	372/45	257/76
11	<input checked="" type="checkbox"/>	<input type="checkbox"/>	US 6614822 B2	20030902	24	Semiconductor laser devices, and semiconductor laser modules and optical	372/45	372/49; 372/99